



520.34403CV4

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. MASUDA, et al
Serial No.: 09/421,043
Filed: October 20, 1999
For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD
Group: 1763
Examiner: A. Mulero

AMENDMENT

Mail Stop: Amendment (Fee)
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 2, 2006

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application in response to the Office Action dated May 2, 2006. The amendments are listed below.

Amendments to the Specification;

Amendment of the Claims; and

Remarks are included following the amendments.